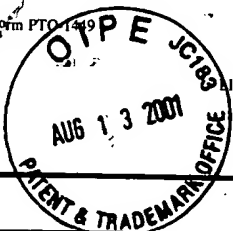


Form PTO-1499

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March 28, 2001GROUP
2812

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>MSL</i>	AA 5,149,615	9/92	Chakravorty et al.			
<i>MSL</i>	AB 5,808,854	9/98	Figura et al.			
<i>MSL</i>	AC 5,559,666	9/96	Figura et al.			
<i>MSL</i>	AD 5,464,786	11/95	Figura et al.			
<i>MSL</i>	AE 5,654,224	8/97	Figura et al.			
<i>MSL</i>	AF 5,266,519	11/93	Iwamoto			
	AG					
	AH					
	AI					
	AJ					
	AK					

FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
<i>MSL</i>	AL EP 0 923 125 A	6/16/99	EP				
<i>MSL</i>	AM EP 0 542 262 A	5/19/93	EP				
	AN						
	AO						
	AP						

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

<i>MSL</i>	AR	"Monolithic Integration of 3-D Electroplated Microstructures with Unlimited Number of Levels Using Planarization with a Sacrificial Metallic Mold"; Yoon et al.;
		IEEE International Micro-Electro Mechanical Systems Conference; 1999; pps. 624 & 627-629.
	AS	
	AT	

EXAMINER

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